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Date : August 22, 2008  
TO : Director, Office of Patent Publication  
FROM : Office of Petitions  
SUBJECT : Withdrawal from Issue of Application No.10/787,120  
  
Applicant(s) : Koichiro Tanaka et al  
Application No. : 10/787,120  
Filed : February 27, 2004

The above-identified application has been assigned Patent No. 7,419,889 and an issue date of September 2, 2008.

It is hereby directed that this application be withdrawn from issue at the request of the applicant. Do not refund the issue fee.

The following erratum should be published in the Official Gazette if the above-identified application is published in the OG of September 2, 2008:

"All reference to Patent No. 7,419,889 to Koichiro Tanaka et al of Japan for LASER IRRADIATION METHOD, LASER IRRADIATION APPARATUS, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE appearing in the Official Gazette of September 2, 2008 should be deleted since no patent was granted."

  
Karen Creasy  
Petitions Examiner  
Office of Petitions

cc: Paul Harrison  
Deneise Boyd  
Mary Louise McAskill  
Niomi Farmer  
Mary E. Johnson (Cookie)  
Duane Davis (CDS)  
Brad Harris  
Kim Terrell  
Lamont Fletcher